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Atty. Dkt. No. 025311-0114

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: Satoshi KUME  
Title: APPARATUS AND METHOD OF  
CLEANING A SUBSTRATE  
Appl. No.: 10/050,161  
Filing Date: 01/18/2002  
Examiner: Michail Kornakov  
Art Unit: 1746

**RESPONSE TO RESTRICTION REQUIREMENT**

Mail Stop NON-FEE AMENDMENT  
Commissioner for Patents  
PO Box 1450  
Alexandria, Virginia 22313-1450

Sir:

In response to the restriction requirement set forth in the Office Action mailed February 17, 2004, Applicant hereby provisionally elects Group I, Claims 1-7 drawn to a substrate cleaning apparatus, for examination.

Applicants, of course, reserve the right to file one or more divisional applications covering the subject matter of the non-elected claims.

Applicants respectfully request examination on the merits of this application. If the Examiner believes, for any reason, that personal communication will expedite prosecution of this application, the Examiner is invited to telephone the undersigned at the number provided.

Respectfully submitted,

Date

3/8/04

By

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